

Summary

5 According to a first aspect, the present invention relates to a device for depositing a high temperature superconductor onto a substrate in vacuum comprising a refilling device for containing a stock of high temperature superconductor material, an evaporation device, that evaporates the high temperature superconductor material within an evaporation zone by means of an energy transferring medium, and a conveyor that transports the high temperature superconductor material continuously from the refilling device to the evaporation zone in such a way that the high temperature superconductor material delivered into the evaporation zone is evaporated essentially without residues.

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15 According to a further aspect, the present invention relates to a method to evaporate a high temperature superconductor coating onto a substrate in vacuum, comprising the steps of continuous delivery of granular high temperature superconductor material into an evaporation zone and the operation of a beam of an energy transferring medium, so that the delivered granulate is evaporated in the evaporation zone essentially without residues.

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(Fig. 1)

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